



PATENT  
Attorney Docket No.: SLM-04300

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Jahja I. Trisnadi  
Serial No.: 09/498,703  
Filed: February 7, 2000

For: **METHOD AND APPARATUS FOR  
REDUCING LASER SPECKLE  
USING POLARIZATION  
AVERAGING**

) Group Art Unit: 2828  
) Examiner: Armando Rodriguez

**SUPPLEMENTAL INFORMATION  
DISCLOSURE STATEMENT**

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Commissioner for Patents  
P.O. Box 1450  
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Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

United States Patents or Published Patent Applications have been filed electronically (EFS ID # 43749);(EFS ID #43750); (EFS ID #43751); (EFS ID #43752); (EFS ID #43753); (EFS ID #43754); (EFS ID #43755); (EFS ID #43756); (EFS ID #43757); (EFS ID #43758); (EFS ID #43759); (EFS ID #43760); (EFS ID #43762); (EFS ID #43763); (EFS ID #43764); and (EFS ID #43765).

Applicants have become aware of the following printed publication which may be material to the examination of this application:

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This Supplemental Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,  
HAVERSTOCK & OWENS LLP

Dated: 7-16-03

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EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Applicant: Jahja I. Trisnadi

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## FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

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		Filing Date: February 7, 2000		Group Art Unit: 2828		

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JUL 21 2003 PATENT & TRADEMARK OFFICE	Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
						Yes	No
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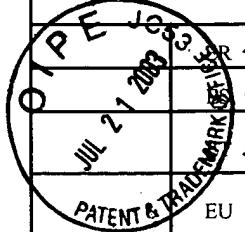
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Payne et al., "Resonance Measurements of Stresses in Al/Si<sub>3</sub>N<sub>4</sub> Micro-Ribbons", Silicon Light Machines, September 22, 1999, 11 pgs.</td> </tr> <tr> <td>HL</td> <td>M. W. Miles, "A New Reflective FPD Technology Using Interferometric Modulation", 4 pgs.</td> </tr> <tr> <td>HM</td> <td>N. A. Riza et al., "Digitally Controlled Fault-Tolerant Multiwavelength Programmable Fiber-Optic Attenuator Using a Two-Dimensional Digital Micromirror Device", OPTICS LETTERS, March 1, 1999, Vol. 24, No. 5, pp. 282-284.</td> </tr> <tr> <td>HN</td> <td>N. A. Riza et al., "Synchronous Amplitude and Time Control for an Optimum Dynamic Range Variable Photonic Delay Line", APPLIED OPTICS, April 10, 1999, Vol. 38, No. 11, pp. 2309-2318.</td> </tr> <tr> <td>HO</td> <td>P. 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